



A Novel Approach of Improving the Performance Enhancement of InAs/Si Tunnel FET

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ABSTRACT: The designed InAs/ sietrojunction double gate tunnel FET (H-DGTFET) is a type of tunnel FET which only gives a moderate performance enhancement in MOSFET technology. Through this project we can improve the performance enhancement of InAs/Si. For this we analyse the threshold voltage, gate dielectric, channel length. Here the threshold voltage of the device is extracted by using a constant current method. DC characteristics and analog RF performance are investigated for different doping profiles. A highly doped layer is placed in the channel near the source- channel junction, and this decrease the width the depletion region ,which improves the ON-current (I_{on}) and the RF performance further more we use Tunnel FETs with a high-k gate dielectric which have a smaller threshold voltage shift than those using SiO_2 ,while the threshold slope for fixed values of V_g remains nearly unchanged .here three types of tunnel fets are simulated. homogeneous structure ,heterogeneous structure and pnpn model of tunnelfet are the main three structures. Comparing these structure different doping will give much more current and high performance characteristics. Through this a new novel model of tunnelfet structure has been simulated.

KEYWORDS: Hetrojunction tunnel fet; Material; InAs/Si; Homojunction tunnel fet.

I. INTRODUCTION

As we know that CMOS technology is growing day by day. For the better performance enhancement various parameters are taken and modelled . This will result the low power high frequency application transistor. Compare to MOSFET,TUNNEL FET gives the better on current and the performance characteristics of the tunnel fet is much higher.

Generally a good transistor for better performance should satisfies the three main conditions.

- Steepness
- On/off ratio
- Current density /conduction density

Steepness is the minimum switching that willposses a transistor. Generally the value steepness is 60mv/Dec. Decreasing this will value will result the good performance and high on/off ratio. On/off ratio will give the amount of current that is used to operate the transistor. This value also needed to be high. Generally the ratio is $10^6:1$.current density is generally used for miaturizationthe old specification is 1v:1Ma.new is 1 milli-mho/micro. For the better steepness there are two methods

- Modulate the tunnelling barrier
- Density of the state switches

Modulation of the tunnelling barrier is occur by giving reverse voltage or gate voltage. But this will reduces the current density. For the better current density increase the thickness by doping this will give good steepness. If the alignment of the conduction and valence band are perfect ,the conduction rate will become high. Thus through density of the state switches the barrier become thin and the get good steepness .

Another important parameter of good transistor is the material which chosen. Here 2 different structures are considered.

- Homogeneous structure
- Heterogeneous structure



International Journal of Innovative Research in Computer and Communication Engineering

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Vol. 5, Issue 4, April 2017

The better performance enhancement is generally depend on the barrier width ,as the width of the barrier decreases the current increases. Through heterogeneous structure the barrier width is reduced. Thus we obtain a high current from heterogeneous structure compare with homogeneous. Additional to this two gate are provided. This will result in the formation of bilayer heterogeneous strucute.through this tunnelling occur over a large overlap region rather than just at the source to drain channel region. Also

- Provide highest on state conductance,Dopant diffusion
- Dopant placement
- Implant damage
- Eliminates parasitic paths (improved electrostatic design.

In order to increase the current we need to change the doping profile, material, structure. Through this project the current will be increased by changing doping profile.

II. RELATED WORK

Tunnel field-effect transistor (TFET) devices are gaining attention because of good scalability and they have very low leakage current. However, they suffer from low ON-current and high threshold voltage. In this paper, we present III–V heterojunctionless TFET (H-JLTFET) for circuit applications. [1] This paper elaborates on interfacing of III–V with group IV semiconductors for heterojunction. Implementing heterojunction and band gap engineering, we found that devices have significantly improved performance with very high speed even at very voltage. As there is no doping junction present, future scaling could be feasible along with much higher speed of charge carriers than in silicon[1].

First, heterojunction engineering is done to find the optimized position of junction for III–V and IV semiconductors. Afterward, bandgap engineering is incorporated for the selection of materials at drain and source sides for this optimized junction position. It has advantage of high mobility and flexibility over huge range of bandgaps so that optimizations of I_{ON} , I_{ON}/I_{OFF} , and sub threshold slope are easy. Sub threshold slope drops significantly along with very low OFF-current and high ON-current, which reduces power–delay product.[1].

The devices simulated here have been designed to be compatible with this type of processing, to make integration with CMOS possible and to keep costs low. The materials can be deposited with bulk-deposition methods, such as chemical vapour deposition (CVD), rather than expensive techniques, such as molecular beam epitaxy (MBE).[3]

By providing tremendous characteristics along with size scaling we can improve the characteristics. Potential applications of this transistor include static RAM, dynamic RAM, and flash memory device However, low improvement in subthreshold slope hinders junctionless field-effect transistor (JLFET)from many applications. Tunnel field-effect transistors (TFETs) attracted attention for low-power applications with low subthresholdslope but its low ON-current impedes further high speed applications. Other options include germanium channel, strained silicon, III–V material channel, and so on, to surpass the issue of low ON-current. Fabrication concerns eliminate strained silicon, while in germanium; the OFF-state tunneling due to low bandgap brings significant current [1]

III. DESIGN AND SIMULATION SETUP

The three schematic structure of the device are shown in the figure ...here the result are simulated by using TCAD SILVACO ATLAS tool. The three structure contain same base structure but different in material composition as well as doping .operation of the device is based on the intrinsic channel region which is related to the source and drain.as the structure changes the current value also changes.

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Vol. 5, Issue 4, April 2017

A. Homogenous structure

Fig3.(a) Shows the homogeneous structure of the developed model.in which the material for source ,drain and the for channel are same. This is the simplest and quick process of developing a sample n+layer homogeneous structure.as the gate voltage increases from 1v to 10v,the width of the barrier become decreases. Thus conduction will increase and the overall performance also increases.

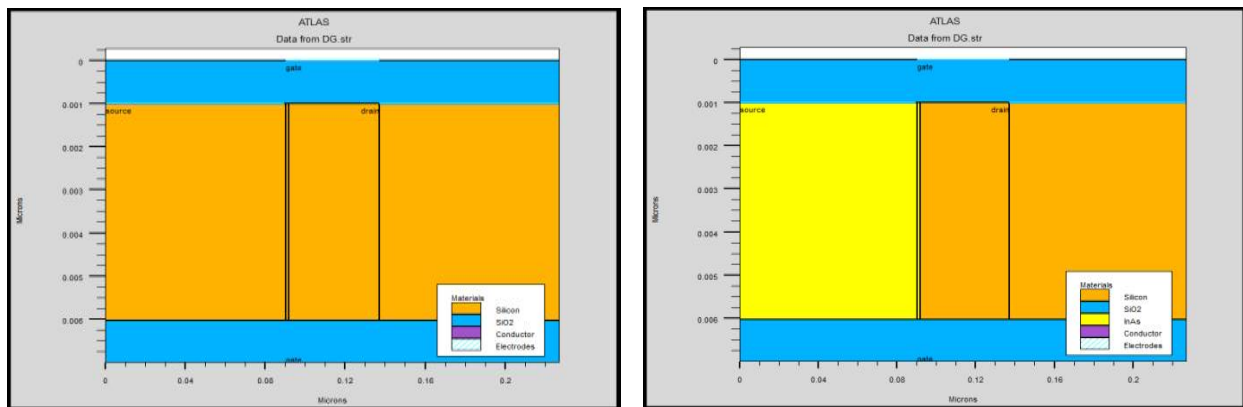


Fig.3(a),(b) shows the homogeneous ,heterogeneous tunnelfet

B. Heterogeneous structure

The main aim of the cmos technology is making a device with lowpowerand giving maximum current at low voltage.by using heterogeneous structure tunnel fet as shown in figure 3(b).the current will change gradually. Thus mostly we are using heterogeneous structure. Material which is using here are InAs/Si.the source is heavily doped with 1×10^{20} n type material .and the channel length is 45nm.the heavily doped region is composed of 2nm width of InAsn+material.and the doping concentration is 1×10^{18} .Drain and the channel uses silicon material with doping concentration of 1×10^{17} n type and p type material oxide thickness is 1nm and the permittivity is 1.21 with work function 4.56.compare to homojunction and hetrojunction doping profile changed structure of tunnelfet have better performance.

IV. RESULT AND DISCUSSION

This region elaborate the comparison between proposed npn model with the heterogeneous and the homogeneous model of tunnel fet.

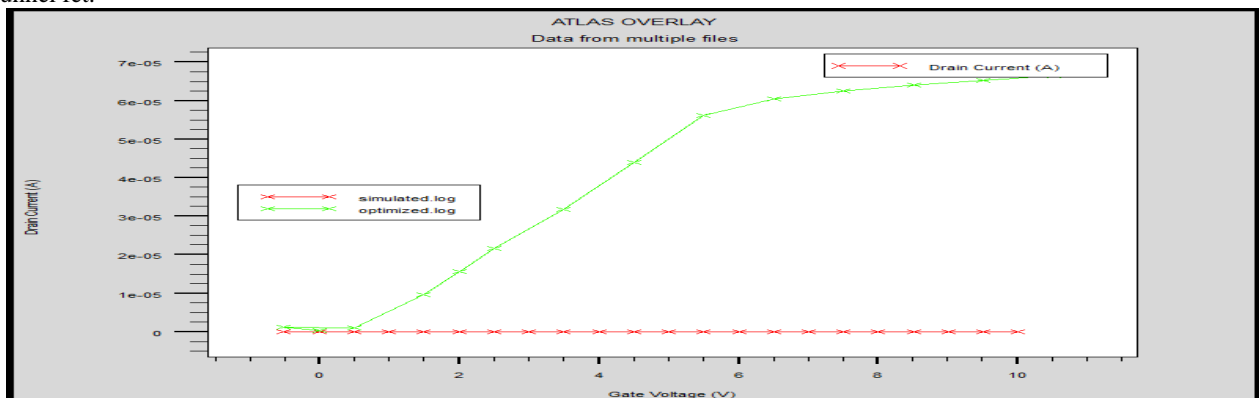


Fig.4(a) the drain current versus gate voltage graph of homogeneous tunnel fet.

International Journal of Innovative Research in Computer and Communication Engineering

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Vol. 5, Issue 4, April 2017

As the model parameters, device structure changes the DC characteristics also changes. Here figure shows the drain current versus gate voltage of three structures. From the figure..4(a) it is clear that there is a small current increase in homogeneous structure .since the original tunnel fet will gave only less than 10nm ampere current. From the homogeneous structure the as shown in figure 4(b) again the current increase from nm to micro ampere.in the homogeneous structure the maximum current obtained is 7×10^5 A.in heterogeneous structure the maximum current obtained is 100micro A. as the size of the structure decreases the subthreshold value also decreased.After optimization with doping the maximum current achieved is 5mA.The fig4.(c) shows the optimized value of hetrojunction tunnelfet.

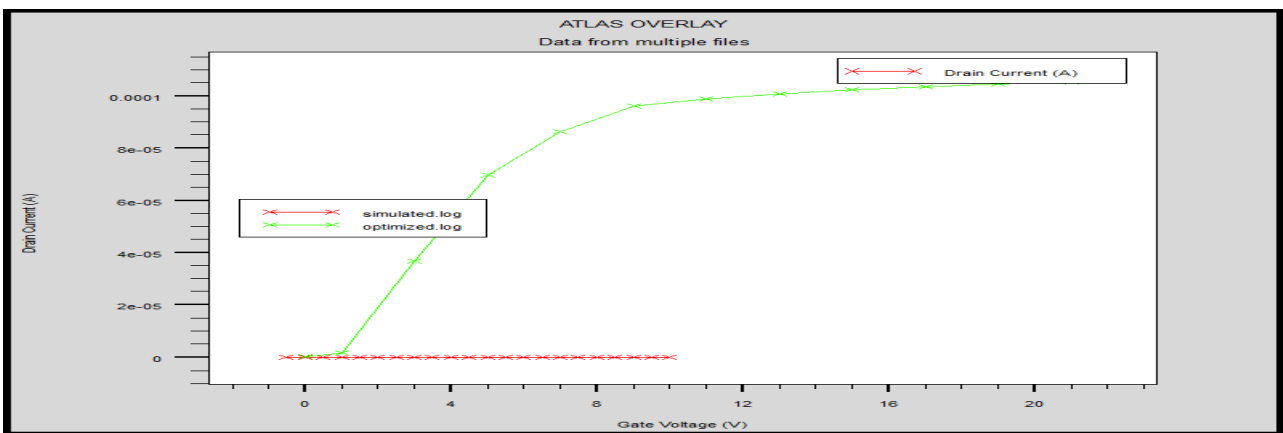


Fig.4(b)the drain current versus gate voltage of hetrojunction InAs/Si tunnel fet.

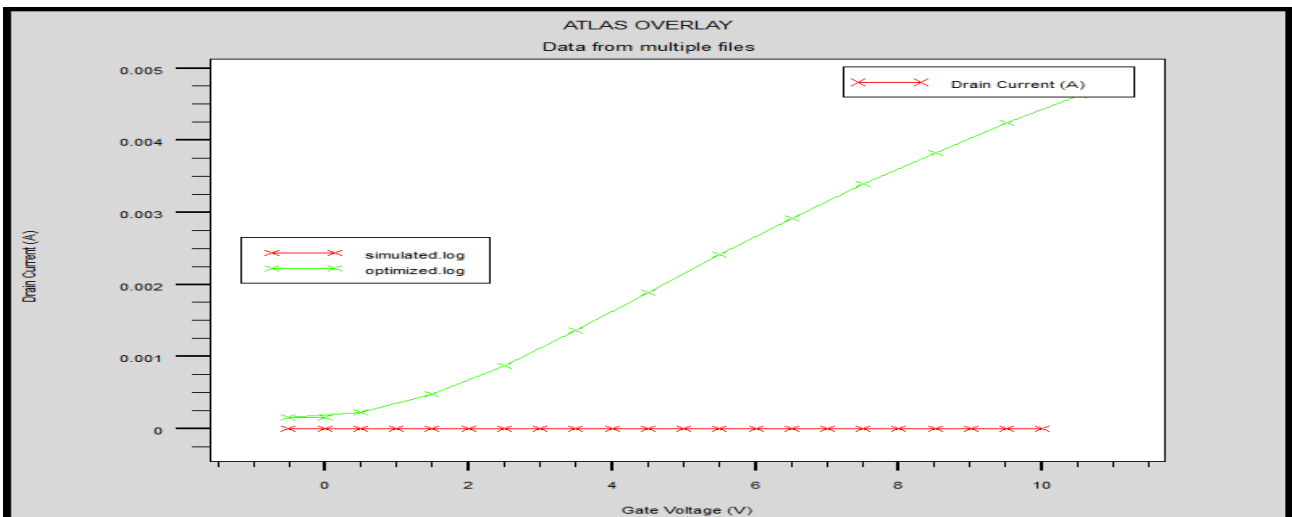


Fig.4(c)the drain current versus gate voltage of new structure hetrojunction InAs/Si tunnel fet.

V. CONCLUSION AND FUTURE WORK

The simulation results showed that the proposed structure of InAs/Si performs better than the structure which are already exist. Different structures of tunnel fetes are analysed to get the better current. Homojunction tunnel fet and hetrojunction tunnel fet of InAs/Si are taken and which are again compared with the PNP tunnel fet model. By combining three structure a large variation of current is obtained from the proposed structure of tunnel fet. Different doping characteristics are also added. Thus the current gradually increased from 100 mA to 5mA.



ISSN(Online): 2320-9801
ISSN (Print): 2320-9798

International Journal of Innovative Research in Computer and Communication Engineering

(An ISO 3297: 2007 Certified Organization)

Website: www.ijirccce.com

Vol. 5, Issue 4, April 2017

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BIOGRAPHY

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